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PATENT

Attorney Docket No. 006915 P10
RW Ref. No. APM/009-03

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Dan MAYDAN, et al.

Entitled: FABRICATION OF SILICON-ON-
INSULATOR STRUCTURE USING PLASMA
IMMERSION ION IMPLANTATION

Serial No.: 10/786,410

Filing Date: February 24, 2004

)
) Group Art Unit: 1763

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) Examiner: Unknown
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)
)
)
)

INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97(b)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Attached hereto is Form PTO-1449 listing documents believed relevant to the subject application. It is respectfully requested that these documents be made of record and an initialed copy of each form be returned to the undersigned.

No representation is made that more pertinent material is not available or should not be considered by the Examiner. It is expected that the Patent and Trademark Office will independently conduct a complete search of appropriate art. Furthermore, no admission is being made that these documents are prior art, and applicant reserves the right to challenge any such consideration.

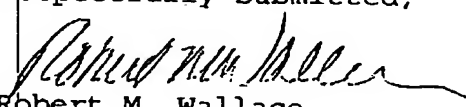
It is believed that this disclosure complies with the requirements of 37 CFR 1.56, 1.97, and 1.98, and the Manual of Patent Examining Procedures, section 609 and 707.05. If for some reason the Examiner considers otherwise, it is respectfully requested that the undersigned be called so that any deficiencies can be remedied.

BEST AVAILABLE COPY

A copy of each foreign patent document and/or non-patent literature is enclosed. Some of the documents may have markings on them. No significance is meant to be attached to the markings. These documents are not necessarily analogous art.

Respectfully submitted,

Dated: 12/10/04


Robert M. Wallace
Registration No. 29,119
Attorney for Applicants
Customer No. 000044843

Robert M. Wallace
Patent Attorney
2112 Eastman Avenue, Suite 102
Ventura, CA 93003
(805) 644-4035

Sheet 1 Of 1

FORM PTO-1449

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICE

Attorney Docket No.: 006915 P10 Serial No.: 10/786,410

Applicant(s): Dan MAYDAN, et al.

Filing Date: 02-24-2004

Group: 1763

LIST OF PRIOR ART CITED BY APPLICANT

(Use several sheets if necessary)

U. S. PATENTS

Initials	Patent No	Issue Date	Name	Class	Subclass	Filing Date
	US-4,510,672	04-16-1985	YAKURA ET AL.	21	225	04-16-85
	US-4,914,500	04-03-1990	LIU ET AL.	357	67	04-03-90
	US-5,136,969	08-11-92	CHAPMAN	118	305	01-25-91
	US-5,840,589	11-24-1998	WARNER, JR. ET AL.	437	128	06-06-95
	US-5,918,140	06-29-1999	WICKBOLDT ET AL.	438	535	06-16-97
	US-6,190,979 B1	02-20-2001	RADENS ET AL.	438	301	06-12-99
	US-6,312,999 B1	11-06-2001	CHIVUKULA ET AL.	438	303	03-29-01
	US-6,475,859 B1	11-05-2002	TEWS ET AL.	438	243	06-13-00
	US-6,500,741 B2	12-31-2002	BUCHANAN ET AL.	438	558	03-28-02
	US-6,506,653 B1	01-14-2003	FURUKAWA ET AL.	438	305	03-13-00
	US-6,566,192	05-20-2003	LIN	438	243	02-07-02
	US 2002/0197806 A1	12-26-2002	FURUKAWA ET AL.	438	305	08-16-02
	US 2003/0134469 A1	07-17-03	HORZEL ET AL.	438	249	01-27-03
	US 2004/0077157 A1	04-22-04	CHAKRAVARTHI ET AL.	438	510	10-02-03

Initials	Other Documents (Title, Author, Date, Pages, Etc., if known)
	Huff, H. and Zeitzoff, Peter M., "An analytical look at vertical transistor structures", <i>Solid State Technology</i> , pp. 59-72, August 2004.

Examiner's Signature:

Date Considered:

Initial if reference was considered, whether or not citation with MPEP. Mark through citation if not considered. Include a copy of this citation form with your next correspondence to the Applicant(s).

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Please acknowledge receipt of the following:

USPTO Transmittal Form (1 page), Information Disclosure Statement under 37 CFR 1.97(b) (2 pages), Form PTO-1449 (1 page), one (1) cited non-patent literature document, return receipt postcard (2)

Applicant : DAN MAYDAN ET AL.
 Serial No. : 10/786,410
 Filed : February 24, 2004
 For : FABRICATION OF SILICON-ON-INSULATOR
 STRUCTURE USING PLASMA IMMERSION
 ION IMPLANTATION
 Docket No. : 006915 USA P10 (APM/009-03)
 Mailed : NOVEMBER 18, 2004



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